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Docket No.:0756-7244

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT application of )

Koichiro TANAKA, et al. )

Serial No. 10/749,505 ) Group Art Unit: 2828

Filed: January 2, 2004 ) Examiner: A. Rodriguez

For: LASER IRRADIATION METHOD, METHOD )

FOR MANUFACTURING SEMICONDUCTOR )

DEVICE, AND LASER IRRADIATION SYSTEM

**CERTIFICATE OF MAILING**

I hereby certify that this correspondence is being deposited with The United States Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Commissioner for Patents, P. O. Box 1450, Alexandria VA 22313-1450, on April 4, 2006

Henry J. duv

**THIRD REQUEST FOR STATUS**

Honorable Commissioner of Patents

P. O. Box 1450

Alexandria VA 22313-1450

Sir:

To date the undersigned attorney of record has received no action in the above-identified patent application. Please provide the undersigned with a status report of the application in writing.

Respectfully submitted,

  
Eric J. Robinson  
Reg. No. 38,285

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